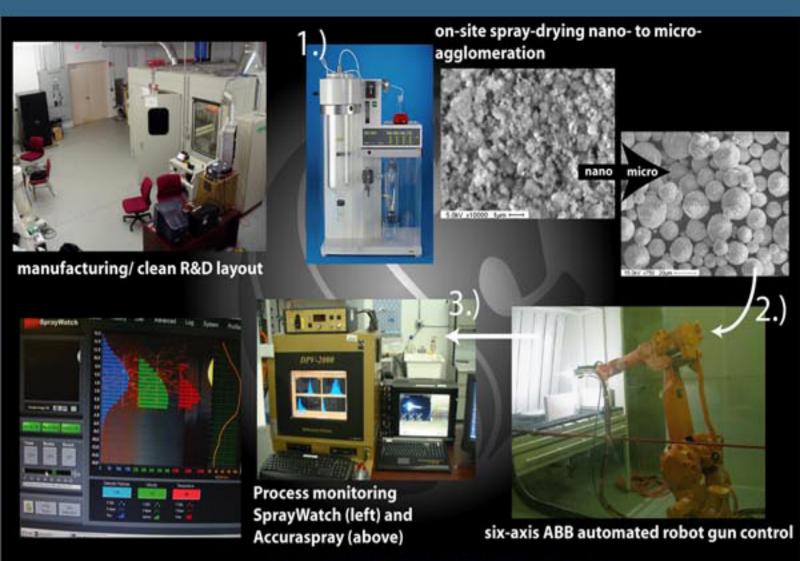
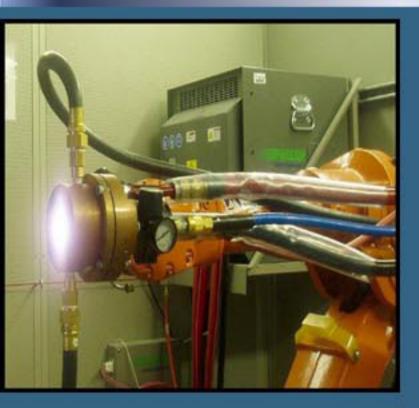
Plasma Facility



DURIP Plasma Nanomanufacturing Laboratory

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PLC based process control

Mass flow gas control

Realtime process control and Graphic user interface

Modular design

On-line diagnostics

Recipe Storage

Engineered for safety

CE compliant

Nitrogen gas shroud applied for spraying Powders with high propensity for oxidation.

Could be used for spraying pyrophoric powders.

Suitable for robot mount and could be used with any plasma spray torches.

Spraywatch



Mean particle velocity, temperature & flow rate.

Plume vertical position and width.

Recording of all measured parameters for off-line analysis.

On-line adjustment of data acquisition parameters.